



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
United States Patent and Trademark Office
Address: COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, Virginia 22313-1450
www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
-----------------	-------------	----------------------	---------------------	------------------

10/579,225

03/24/2008

Risto Kostiainen

Q94898

6385

23373 7590 01/29/2010
SUGHRUE MION, PLLC
2100 PENNSYLVANIA AVENUE, N.W.
SUITE 800
WASHINGTON, DC 20037

EXAMINER

IPPOLITO RAUSCH, NICOLE

ART UNIT

PAPER NUMBER

2881

NOTIFICATION DATE

DELIVERY MODE

01/29/2010

ELECTRONIC

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Notice of the Office communication was sent electronically on above-indicated "Notification Date" to the following e-mail address(es):

sughrue@sughrue.com
PPROCESSING@SUGHRUE.COM
USPTO@SUGHRUE.COM

Office Action Summary	Application No. 10/579,225	Applicant(s) KOSTIAINEN ET AL.	
	Examiner NICOLE IPPOLITO RAUSCH	Art Unit 2881	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☐ Responsive to communication(s) filed on ____.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-29 is/are pending in the application.
- 4a) Of the above claim(s) ____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) ____ is/are allowed.
- 6) ☒ Claim(s) 1-29 is/are rejected.
- 7) ☐ Claim(s) ____ is/are objected to.
- 8) ☐ Claim(s) ____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 12 May 2006 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
 Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
 Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. ____.
 3. ☒ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|----------------------------------------------------------------------------------------|-------------------------------------------------------------------|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. ____. |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| Paper No(s)/Mail Date <u>5/12/2006</u> . | 6) <input type="checkbox"/> Other: ____. |

DETAILED ACTION

Claim Rejections - 35 USC § 112

1. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

2. Claims 2 and 18 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. In this particular instance, "possibly used for" creates an issue wherein it is unclear if the carrier gas must be used for feeding the solution, or not. Also, as the term "carrier gas" has not been used before, there is lack of antecedent basis for this limitation in the claims.
3. Claims 8, 12, 24 and 25 recites the limitation "curtain plate". There is insufficient antecedent basis for this limitation in the claim.

Claim Rejections - 35 USC § 103

4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

5. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was

Art Unit: 2881

not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

6. Claims 1, 2, 3, 4, 5, 6, 7, 10, 11, 12, 13, 14, 15, 16, 17, 18, 19, 20, 21, 27, 28 and 29 are rejected under 35 U.S.C. 103(a) as being unpatentable over Miller et al. (U.S. Patent Application Publication Number 20030146377, from hereinafter "Miller") in view of Syms (U.S. Patent Number 7208729, from hereinafter "Syms").

7. In regards to claim 1, Miller teaches that a solution to be examined is vaporized in a vaporizer (paragraphs 0126, 0128, FIG. 3A paragraphs 0124-0125 discloses heating the flow path, that will lead to vaporization from the heat, furthermore it is an electrospray tip and hence nebulizing takes place), the vaporized sample solution is sprayed using a gas flow (FIG. 13B, tip 20, gas flow 90, paragraph 0154), the ions are separated and directed to a detector (see, i.e., paragraph 0002), and that the vaporizer is fabricated as a micromechanical structure (see, i.e., paragraph 0134).

In regards to claim 1, Miller fails to explicitly teach that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions. However, Miller does teach electrodes immediately outside of the spray region, which could serve to cause corona discharge-assisted ionization (FIG. 13, electrodes 104, paragraph 0154).

Syms teaches that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions (column 4 lines 50-55).

Art Unit: 2881

In view of the teaching of Syms it would have been obvious to one of ordinary skill in the art at the time the invention was made that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions. Corona discharge may serve to heighten the ionization effect, allowing for a better sample that should, in turn, allow for a clearer, more defined mass peak in the final mass analysis.

8. In regards to claim 2, Miller teaches that a vaporizer is used which comprises flow channel networks for the solution and the carrier gas possibly used for feeding the solution (paragraphs 0051, 0061, etc., FIGS. 13, 16, paragraph 0154, etc.), as well as a heater of the vaporizer, which are all included in the monolithic structure (Miller states that this is a MEMS device in, i.e., paragraph 0134, which means that all of the components are integrated on the monolithic structure).

9. In regards to claim 4, though Miller as modified by Syms fails to explicitly teach that the vaporizer and corona discharge zone are integrated into a single micromechanical structure, it would have been obvious. Both Miller and Syms disclose monolithic micromechanical structures that work in mass spectrometry application. Hence, any variation of either Miller or Syms would be modified in such a way that the device continues to be a monolithic micromechanical structure that allows for portability of the device if desired/required.

10. In regards to claim 5, Miller teaches that the micromechanical structure used comprises flow channel networks designed for one or more wafers, and a heater (FIGS. 4A-C, 11, etc. illustrate that it is a wafer structure-that is what a MEMS device is-

Art Unit: 2881

paragraph 0137, for example, discusses flow channels, paragraph 0125 discusses the onboard heaters that assist in desolvation of the sample).

11. In regards to claim 6, Miller teaches a substrate wafer in which flow channel networks for liquid and gases are formed (see, i.e. FIGS. 4A-D, FIG. 11A, 13-13, etc.) and a cover wafer, attached to the substrate in which a heater for vaporizing the sample solution is patterned (heaters are discussed in paragraph 0153-0156, for instance, while FIG. 4B illustrates the wafer 'sectioning').

12. In regards to claim 7, Miller teaches that the vaporized sample is ionized in the presence of air, at normal atmospheric pressure (see, i.e., paragraph 0059).

In regards to claim 7, Miller fails to explicitly teach that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions. However, Miller does teach electrodes immediately outside of the spray region, which could serve to cause corona discharge-assisted ionization (FIG. 13, electrodes 104, paragraph 0154).

Syms teaches that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions (column 4 lines 50-55).

In view of the teaching of Syms it would have been obvious to one of ordinary skill in the art at the time the invention was made that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions. Corona discharge may serve to heighten the ionization effect,

Art Unit: 2881

allowing for a better sample that should, in turn, allow for a clearer, more defined mass peak in the final mass analysis.

13. In regards to claim 10, Miller teaches that polar compounds, non-polar compounds, neutral compounds or ionic compounds are examined, and the sample to be examined is dissolved in a polar or non-polar solvent, used as an eluent, to generate the sample solution (paragraph 0177).

14. In regards to claim 11, Miller as modified by Syms fails to explicitly teach that the molar masses are at most 2000 Da. However it would have been obvious to one of ordinary skill in the art at the time the invention was made that the molar masses are at most 2000 Da, since it has been held that where the general conditions of a claim are disclosed in the prior art, discovering the optimum or working ranges involves only routine skill in the art. See *in re Aller*, 105 USPQ 233.

15. In regards to claim 13, Miller teaches that the sample is ionized using the APCI method (see, i.e., paragraph 0059).

16. In regards to claim 14, Miller teaches that the gas flow used for the injection is brought in essentially perpendicular to the flow direction of the sample (see, i.e., FIG. 13A, paragraph 0154).

17. In regards to claim 15, Miller teaches that the gas flow is fed into the device in the flow direction of the liquid and before the feed opening of the liquid (see, i.e., FIG. 13A, paragraph 0154).

Art Unit: 2881

18. In regards to claim 16, Miller teaches that the gas flow is fed through one feed opening, in order to distribute the gas flow around the liquid flow comprising sample, and, as a result, a homogenous mixture is achieved (see FIG. 13a, for example).

19. In regards to claim 17, Miller teaches that a solution to be examined is vaporized in a vaporizer (paragraphs 0126, 0128, FIG. 3A paragraphs 0124-0125 discloses heating the flow path, that will lead to vaporization from the heat, furthermore it is an electrospray tip and hence nebulizing takes place), that the sample is ionized using APCI (see, i.e., paragraph 0059) a detector to detect the ions (see, i.e., paragraph 0002) a means for directing the charged particles into the detector (FIG. 13A, attractor electrodes 104, paragraph 0154), and that the vaporizer is fabricated as a micromechanical structure (see, i.e., paragraph 0134).

In regards to claim 17, Miller fails to explicitly teach that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions. However, Miller does teach electrodes immediately outside of the spray region, which could serve to cause corona discharge-assisted ionization (FIG. 13, electrodes 104, paragraph 0154).

Syms teaches that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to generate gas phase ions (column 4 lines 50-55).

In view of the teaching of Syms it would have been obvious to one of ordinary skill in the art at the time the invention was made that the sample is placed into a corona discharge zone, where the sample to be ionized is ionized using a corona discharge to

Art Unit: 2881

generate gas phase ions. Corona discharge may serve to heighten the ionization effect, allowing for a better sample that should, in turn, allow for a clearer, more defined mass peak in the final mass analysis.

20. In regards to claim 18, Miller teaches that a vaporizer is used which comprises flow channel networks for the solution and the carrier gas possibly used for feeding the solution (paragraphs 0051, 0061, etc., FIGS. 13, 16, paragraph 0154, etc.), as well as a heater of the vaporizer, which are all included in the monolithic structure (Miller states that this is a MEMS device in, i.e., paragraph 0134, which means that all of the components are integrated on the monolithic structure).

21. In regards to claim 20, though Miller as modified by Syms fails to explicitly teach that the vaporizer and corona discharge zone are integrated into a single micromechanical structure, it would have been obvious. Both Miller and Syms disclose monolithic micromechanical structures that work in mass spectrometry application. Hence, any variation of either Miller or Syms would be modified in such a way that the device continues to be a monolithic micromechanical structure that allows for portability of the device if desired/required.

22. In regards to claim 21, Miller teaches that there is a monolithic block which is formed in two or more parts which are connected to each other (see, i.e., FIG. 4B).

23. In regards to claim 27, Miller teaches that the flow channel system of the carrier gas used for feeding the solution is connected to a feed nozzle gas, which nozzle is located upstream in the flow direction of the solution and through which gas can be fed essentially perpendicular to the flow direction of the solution (see, i.e., FIG. 13A).

Art Unit: 2881

24. In regards to claim 28, Miller teaches that the gas flow is fed through one feed opening, in order to distribute the gas flow around the liquid flow comprising sample, and, as a result, a homogenous mixture is achieved (see FIG. 13a, for example).

25. In regards to claim 29, Miller teaches that the heater comprises heating resistors, the foreparts of which are made wide in order to decrease the flow resistance (FIG. 4A, heating resistors 53r, 55r, paragraph 0124). Though Miller as modified by Syms fails to teach that the resistors are made narrow near the mixing zone of the gas and liquid, it would have been an obvious variant. Doing so would generate a more intense localized heating, if so desired, and perhaps create a more perfect ionization of the sample, thus improving the sample overall and theoretically improving the final mass determination of the sample.

26. In regards to claims 3, 12 and 19, Miller as modified by Syms teaches the invention except for the flow rate ranges of the liquids and gases in the system. It would have been obvious to one of ordinary skill in the art at the time the invention was made to use the disclosed ranges in the instant application, since it has been held that where the general conditions of a claim are disclosed in the prior art, discovering the optimum or working ranges involves only routine skill in the art. See *in re Aller*, 105 USPQ 233. In this instance, the ranges would have to be optimized such that the desired flow of ions are achieved, however, somewhat limited as well. Too high a flow rate could well cause too much pressure inside of the micromechanical device, which could in principle blow it to pieces. Thus, maximizing the flows for the correct ion rate while keeping the rates low enough to avoid damaging the device would have been obvious.

Art Unit: 2881

27. Claims 8-9 and 24-25 are rejected under 35 U.S.C. 103(a) as being unpatentable over Miller as modified by Syms as applied to claims 1 and 17 above, and further in view of Guevremont et al. (U.S. Patent Application Publication Number 20060151694, from hereinafter "Guevremont"). The teachings of Miller and Syms have been discussed above.

28. In regards to claims 8 and 24, Miller as modified by Syms does teach that the corona discharge zone comprises a needle-shaped electrode (see, i.e., FIG. 13a). However, it is not explicitly taught that the needle is connected to a voltage which is so high in relation to the curtain plate of the mass spectrometer that the electric field strength, at least in the immediate vicinity of the tip, exceeds the corona discharge threshold of air.

Guevremont teaches that the needle is connected to a voltage which is so high in relation to the curtain plate of the mass spectrometer that the electric field strength, at least in the immediate vicinity of the tip, exceeds the corona discharge threshold of air (paragraph 0142).

In view of the teaching of Guevremont it would have been obvious to one of ordinary skill in the art at the time the invention was made that the needle is connected to a voltage which is so high in relation to the curtain plate of the mass spectrometer that the electric field strength, at least in the immediate vicinity of the tip, exceeds the corona discharge threshold of air. If this were not the case, ions would not be formed in the corona discharge region. Furthermore, the curtain plate would, if set to high, act to

Art Unit: 2881

further ionize the ions (i.e. create fragments) which may not be desirable, if the voltage were set at too high of a value.

29. In regards to claims 9 and 25, Miller as modified by Syms and Guevremont as discussed above fails to teach that the curtain plate is set to at least 1 kV, while the field strength near the tip of the electrode is set to 50 kV/mm.

However, Guevremont does teach that the curtain plate is set to at least 1 kV, while the field strength near the tip of the electrode is set to 50 kV/mm (paragraph 0142, the entire needle is set at 3 kV, but it is likely to be several millimeters to even inches in length, and hence at the tip, a concentration of 50 kV/mm is possible).

In view of this further teaching of Guevremont it would have been obvious to one of ordinary skill in the art at the time the invention was made that the curtain plate is set to at least 1 kV, while the field strength near the tip of the electrode is set to 50 kV/mm. If this were not the case, ions would not be formed in the corona discharge region. Furthermore, the curtain plate would, if set to high, act to further ionize the ions (i.e. create fragments) which may not be desirable, if the voltage were set at too high of a value.

30. Claims 22-23 and 26 are rejected under 35 U.S.C. 103(a) as being unpatentable over Miller as modified Syms as applied to claim 21 above, and further in view of Apffel et al. (U.S. Patent Number 6649908, from hereinafter "Apffel"). The teachings of Miller and Syms have been discussed above.

Art Unit: 2881

31. In regards to claim 22, Miller does teach that the gas and liquid flows channels are formed in a silicon wafer (paragraph 0121). However, Miller as modified by Syms fails to teach that the heater is formed in glass.

Apffel teaches that the device may be formed in glass (columns 6-7).

In view of the teaching of Apffel it would have been obvious to one of ordinary skill in the art at the time the invention was made that the heater is formed in glass.

Glass is less likely to be damaged from the heat exposure than silicon, as it is a more effective insulator, and so to prevent possible damage to the device, this would have been obvious.

32. In regards to claim 23, Miller teaches that the heater for vaporization is formed in silicon (see, i.e., paragraph 0121. Realistically, wafers usually are made from silicon).

In regards to claim 23, Miller as modified by Syms fails to teach that the gas and liquid flows channels are formed from glass.

Apffel teaches that the gas and liquid flows channels are formed from glass (columns 6-7).

In view of the teaching of Apffel it would have been obvious to one of ordinary skill in the art at the time the invention was made that the gas and liquid flows channels are formed from glass. Glass has a lower coefficient of friction than silicon, and so, the materials will be able to flow more smoothly as a result.

33. In regards to claim 26, Miller as modified by Syms and Apffel fails to explicitly teach that the entire device is fabricated from glass. However, in view of the teaching of Apffel (columns 6-7) it would have been obvious. Glass allows for easier flow of the

Art Unit: 2881

sample materials, while the higher melting point should act to ensure that no damage due to heating the device occurs. In the interest of creating longevity of the device, this would have been obvious.

Conclusion

34. Any inquiry concerning this communication or earlier communications from the examiner should be directed to NICOLE IPPOLITO RAUSCH whose telephone number is (571)270-7449. The examiner can normally be reached on Monday through Thursday 6:30am-5:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Robert Kim can be reached on (571)272-2293. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/N. I./

Application/Control Number: 10/579,225

Page 14

Art Unit: 2881

Examiner, Art Unit 2881

/ROBERT KIM/

Supervisory Patent Examiner, Art Unit 2881